

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L2	2	(rotational adj operation adj quantity) and (input adj device) and (rotation adj angle) and (two adj dimensional)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:54
L3	0	((two adj dimensional) with sensor\$1) and (substrate\$1) and (detection adj electrode\$1) and (elastic adj body) and (conductive adj layer\$1) and (operating adj panel\$1) and (detection adj circuit) and (capacitance adj element\$1)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:58
L4	14170	((two adj dimensional) with sensor\$1)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:58
L5	0	(substrate\$1) and (detection adj electrode\$1) and (elastic adj body) and (conductive adj layer\$1) and (operating adj panel\$1) and (detection adj circuit) and (capacitance adj element\$1)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:58
L6	341	(elastic adj body) and (conductive adj layer\$1)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:58
L7	304	(detection adj circuit) and (capacitance adj element\$1)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:59
L8	0	6 and 7	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:59

L9	2	4 and 6	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:59
L10	10	4 and 7	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:59

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	0	((rotational adj operation adj quantity) with (input adj device) with (rotation adj angle) and (two adj dimensional) adj (force\$1) with (xy adj coordinate\$1) with (rectangular adj coordinate\$1) and (polar adj coordinate\$1) adj (convert\$3) with (sequential\$2 adj converting) with (series) with (polar adj coordinate\$1) and (operation adj quantity adj recognizing) with (variation adj angle) with (coordinate adj angle\$1) with (rotation adj angle) and (two adj dimensional) adj (force) adj (sensor\$1) and (substrate adj upper adj surface) with (xy adj 2D adj rectangular adj coordinate\$1) with (x adj axis) adj (intersect\$3) adj (upper surface) with (y adj axis) adj (intersect\$3) adj (upper surface) and (detection adj electrode\$1) adj (upper adj surface) and (outer adj electrode\$1) adj (upper adj surface) adj (detection adj electrode\$1) and (elastic adj deformable adj body) adj (substrate) with (detection adj electrode\$1) with (outer adj electrode\$1) and (displacement adj conductive adj layer\$1) adj (lower adj surface) with (elastic adj deformable adj body) and (plurality adj capacitance adj element\$1) adj (detection adj electrode\$1) with (displacement adj conductive layer\$1) and (operating adj panel) adj (upper adj surface) with (elastic adj deformable adj body) and (detection adj circuit) with (coordinate\$1 adj xy) with (capacitane adj value\$1) with (detection adj capacitance adj element\$1) and (displacement adj conductive adj layer\$1) adj contact adj (outer adj electrode\$1)).clm.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/04 22:50